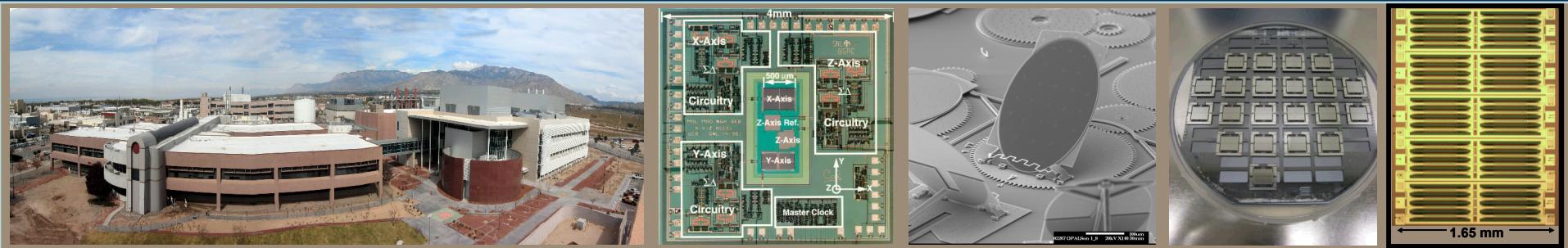


Exceptional service in the national interest

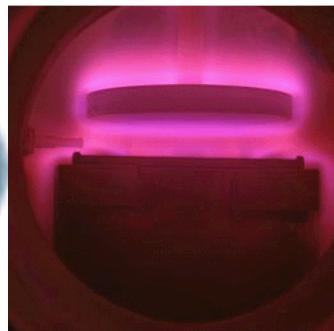
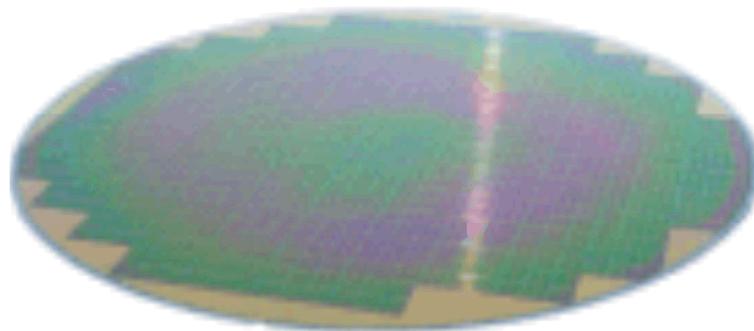
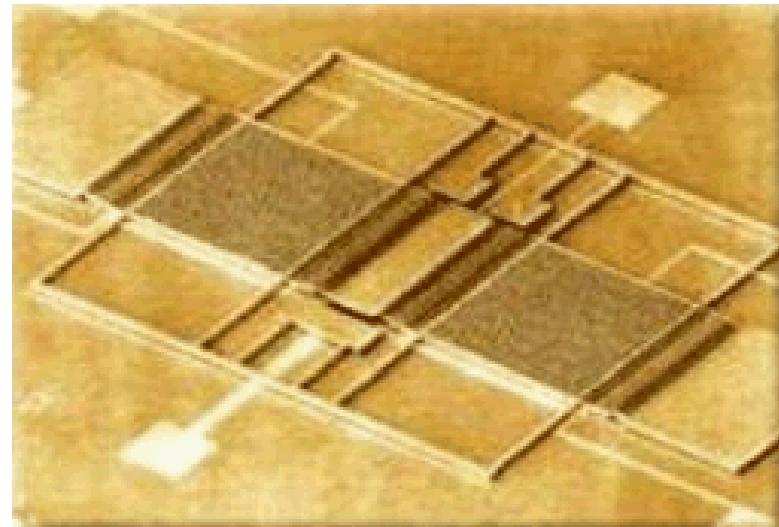
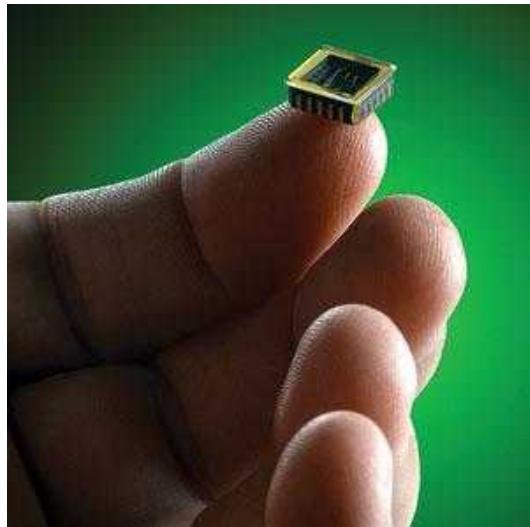


MEMS at Sandia National Laboratories

November 2012

MEMS are “MicroElectroMechanical Systems”

Also known as “microsystems”



The MEMS Technologies Department

Pushing the MEMS technology envelope for national security

R&D for Advanced MEMS

- Mechanisms
- Pressure Sensors
- Inertial Sensors
- Fluidic Components
- Electrical Switches
- RF Switches
- RF Filters
- Mirrors
- Planar Light Wave Circuits
- Solar Cells
- Radiation Detectors



Prototype Development and Limited Production

Core Fabrication Processes

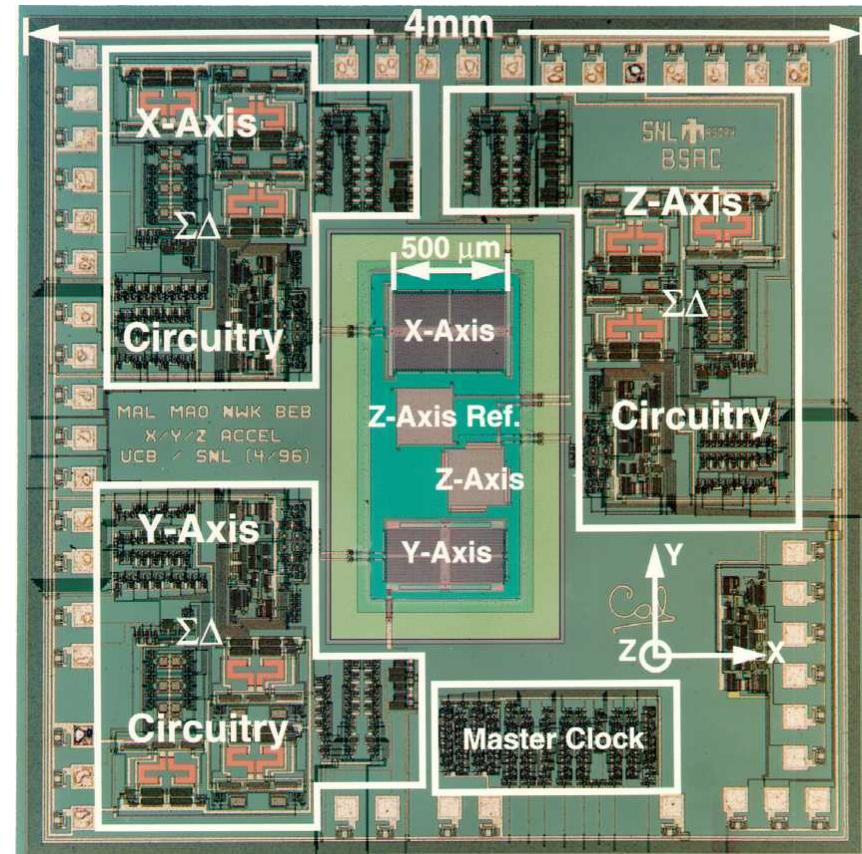
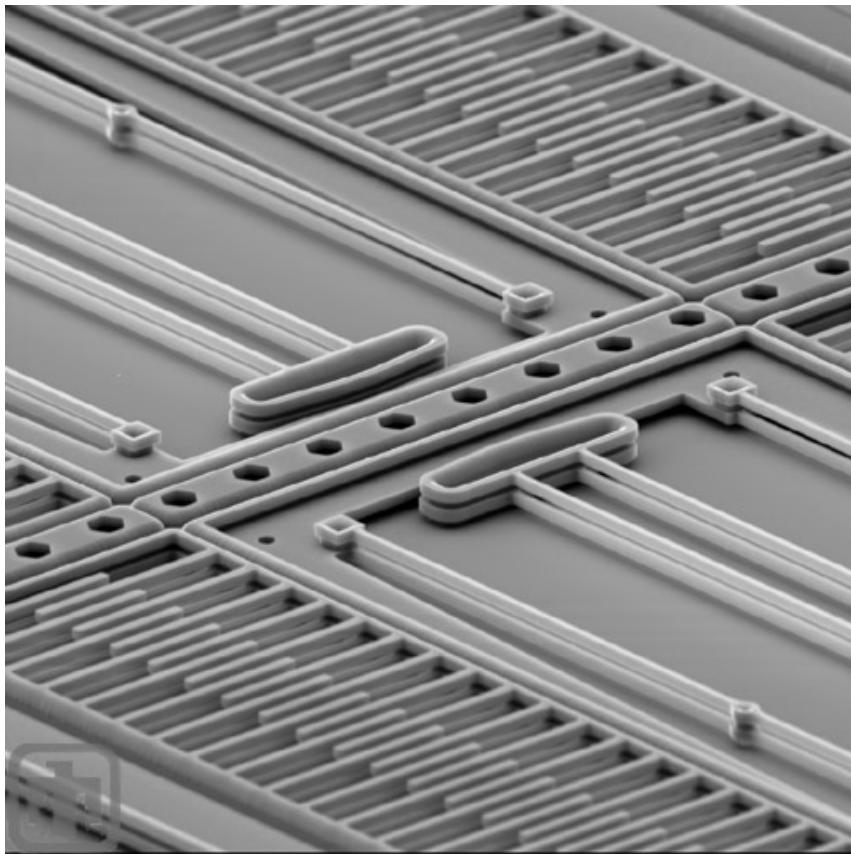
- SUMMiT V™, Baseline plus
 - Silicon Nitride
 - DRIE
 - SOI
 - SFET
- Molded Tungsten
- Aluminum Nitride

Core Technologies

- Design, Layout and Analysis
- Device Testing/Characterization
- Reliability Science and Testing
- Failure Analysis

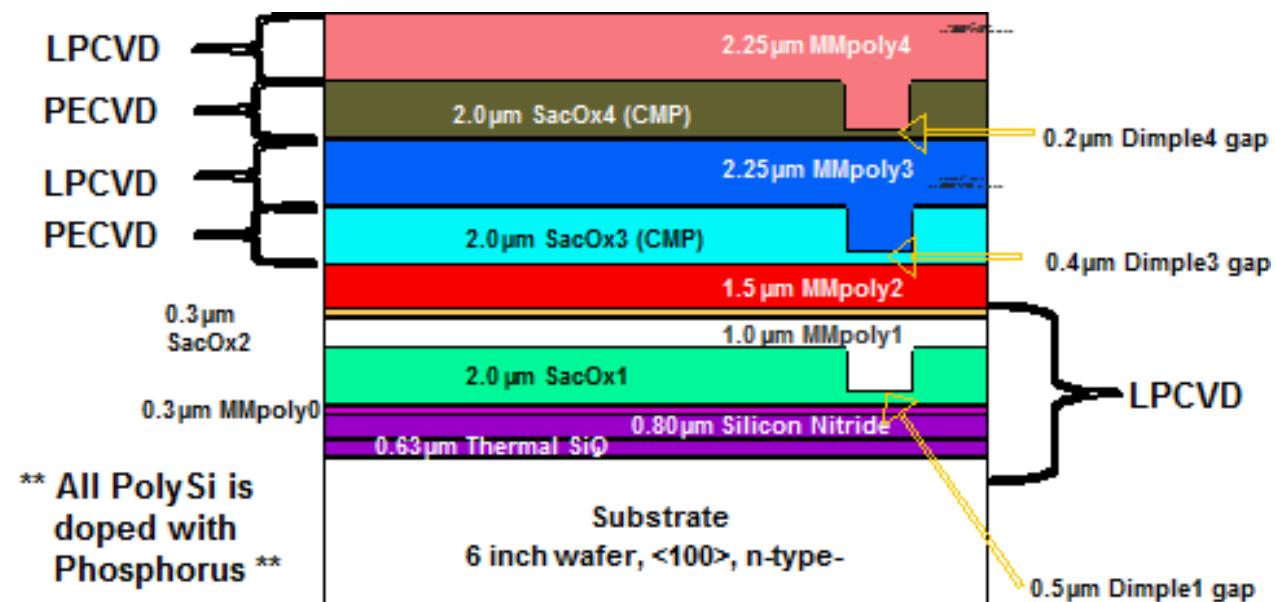
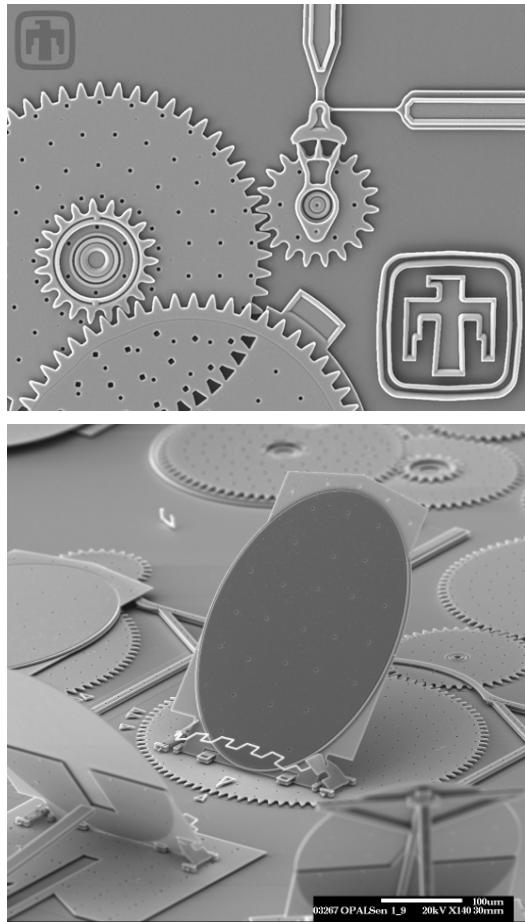
Sandia's Efforts Started in 1990s

Collaboration between semiconductor fab and mechanical designers



SUMMiT V™: A Unique Capability

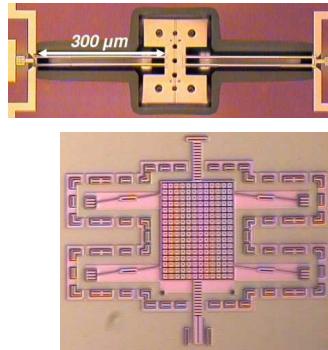
Sandia Ultraplanar, Multilevel MEMS Technology with 5 polysilicon layers



Sandia's Portfolio Today

Exploratory research and advanced development for MEMS technologies, devices, and systems for national security.

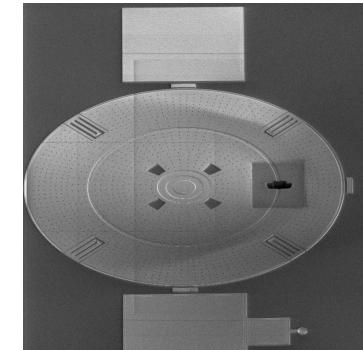
Inertial Sensors



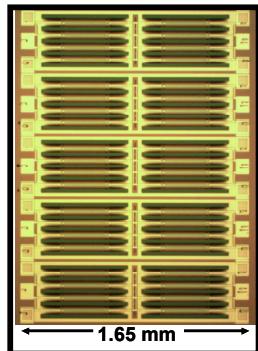
Pressure Sensors



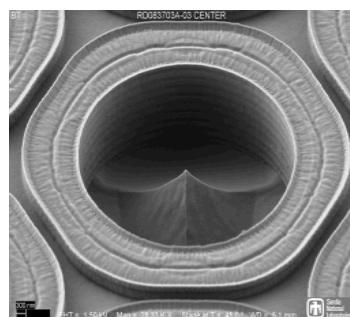
Microfluidic Actuators



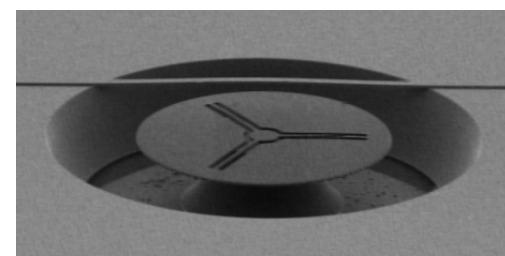
Electronics



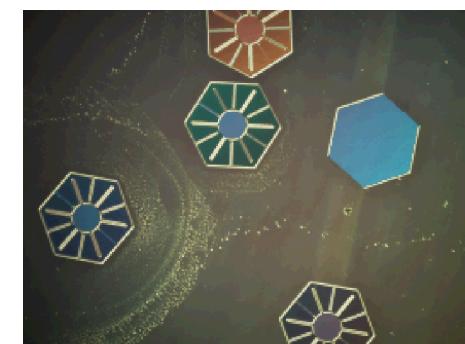
Vacuum Electronics



Photonics and Waveguides

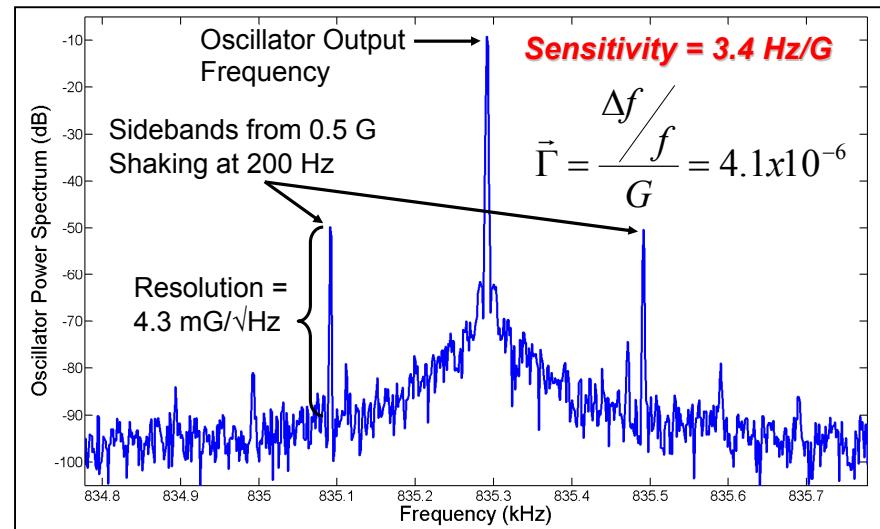
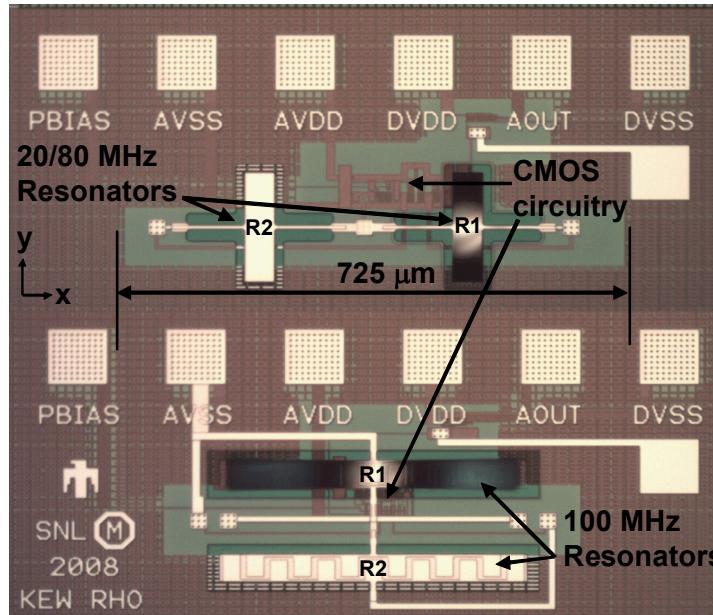
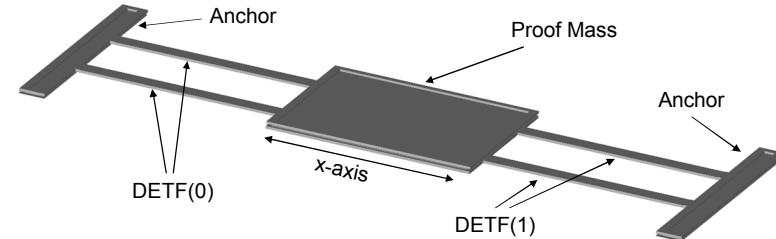
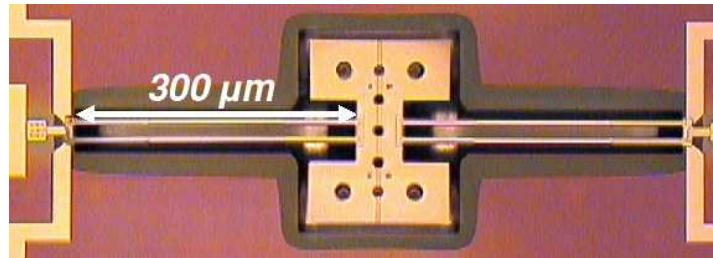


Photovoltaic Cells



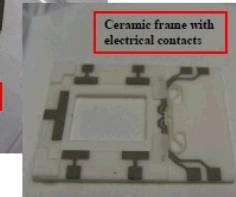
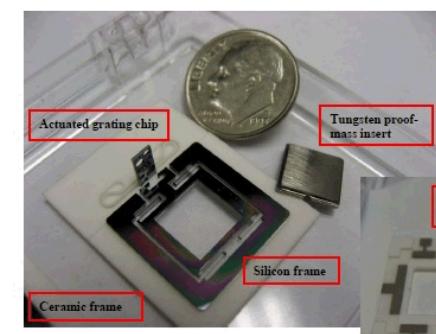
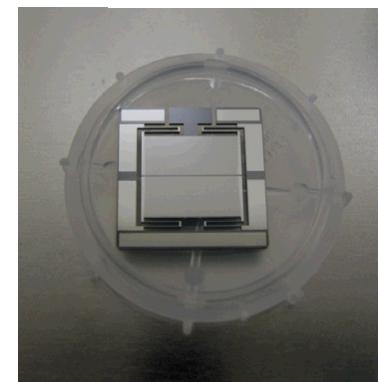
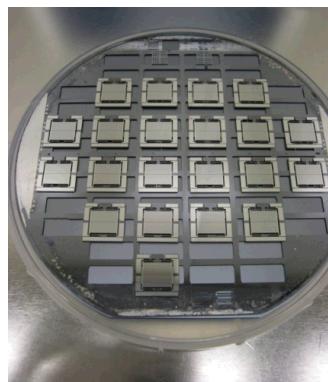
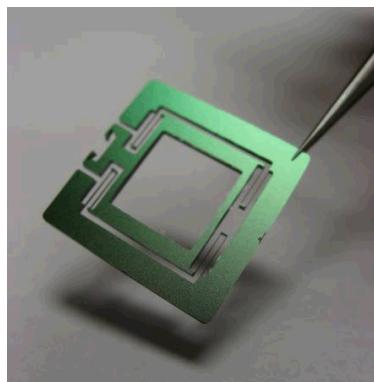
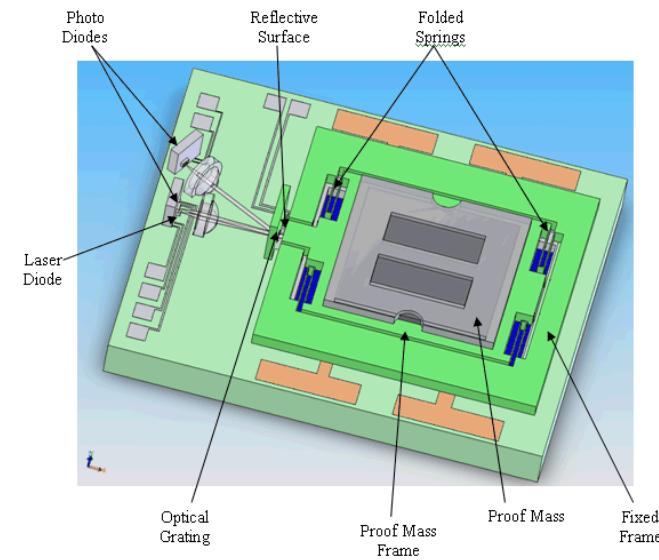
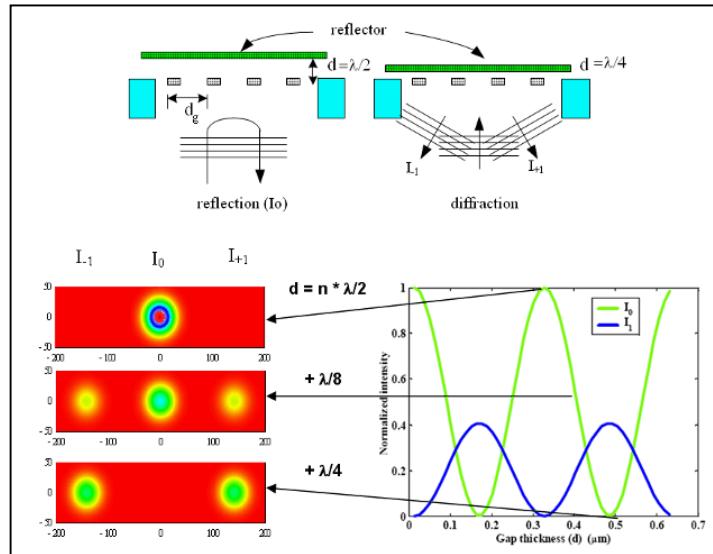
Inertial Sensors: Radiation-Hard

Supporting the core nuclear weapons mission



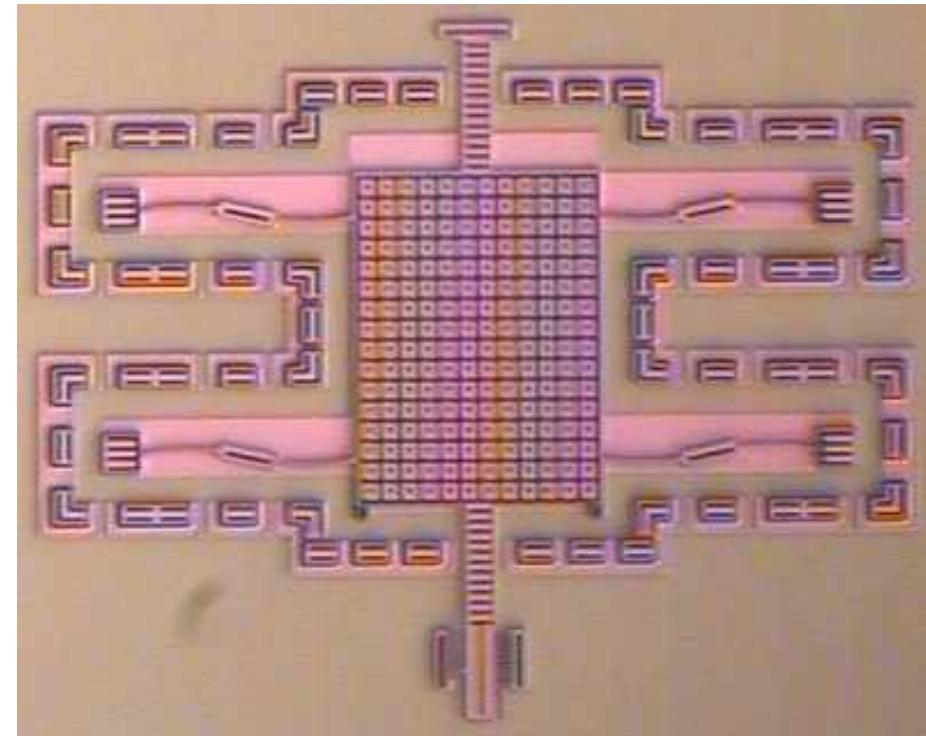
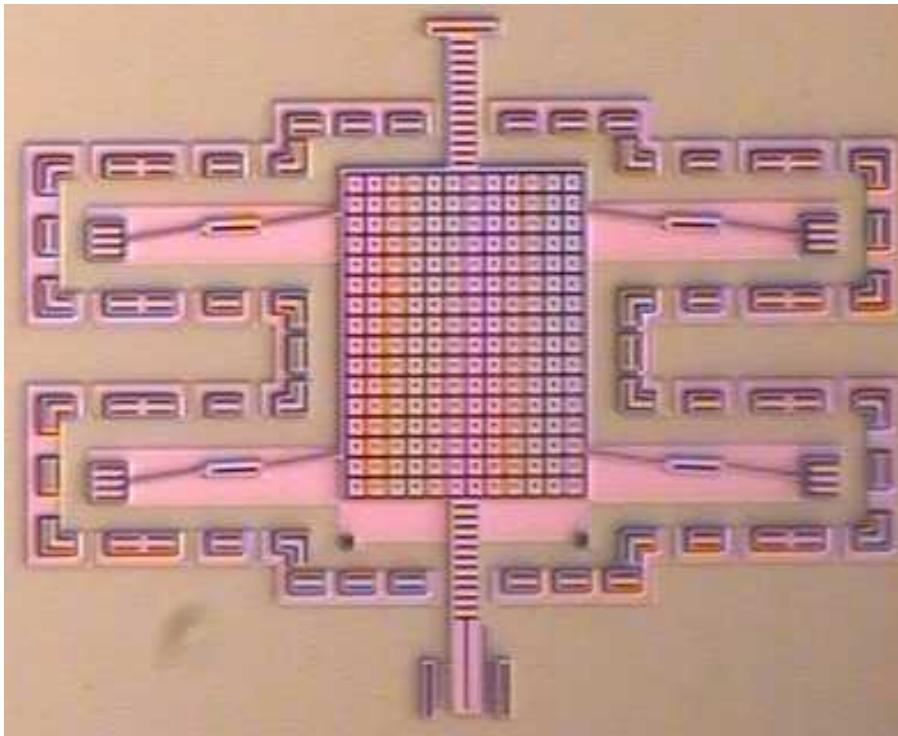
Inertial Sensors: High Performance

Complex fabrication, uneconomical for commercial applications



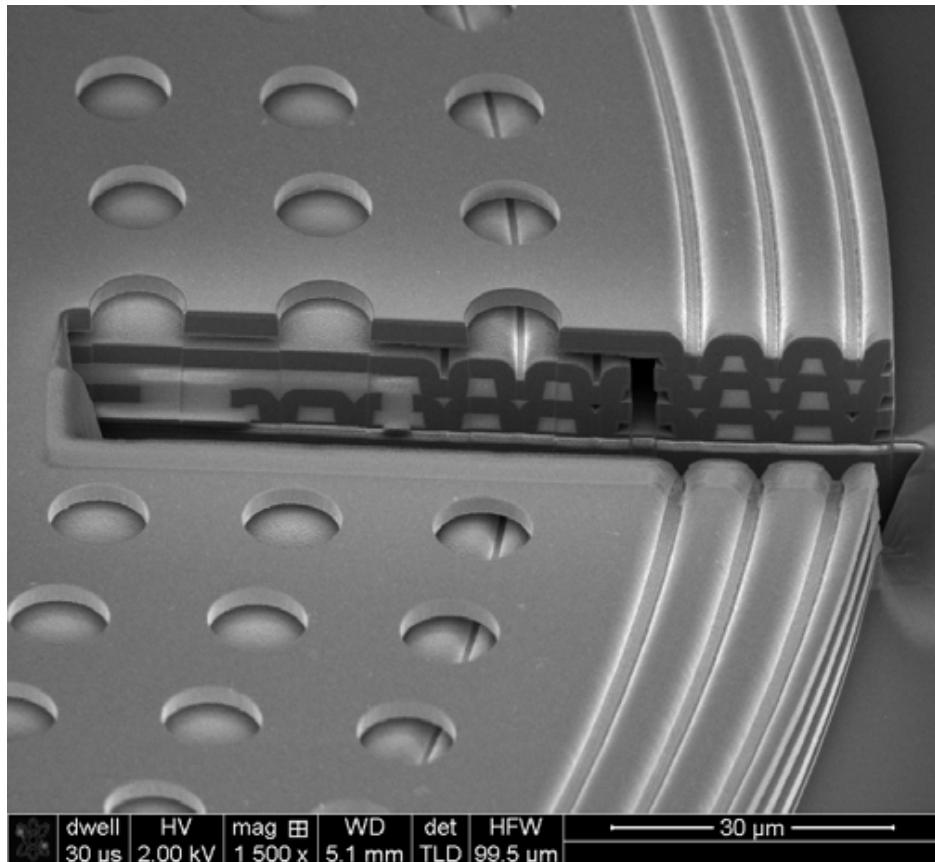
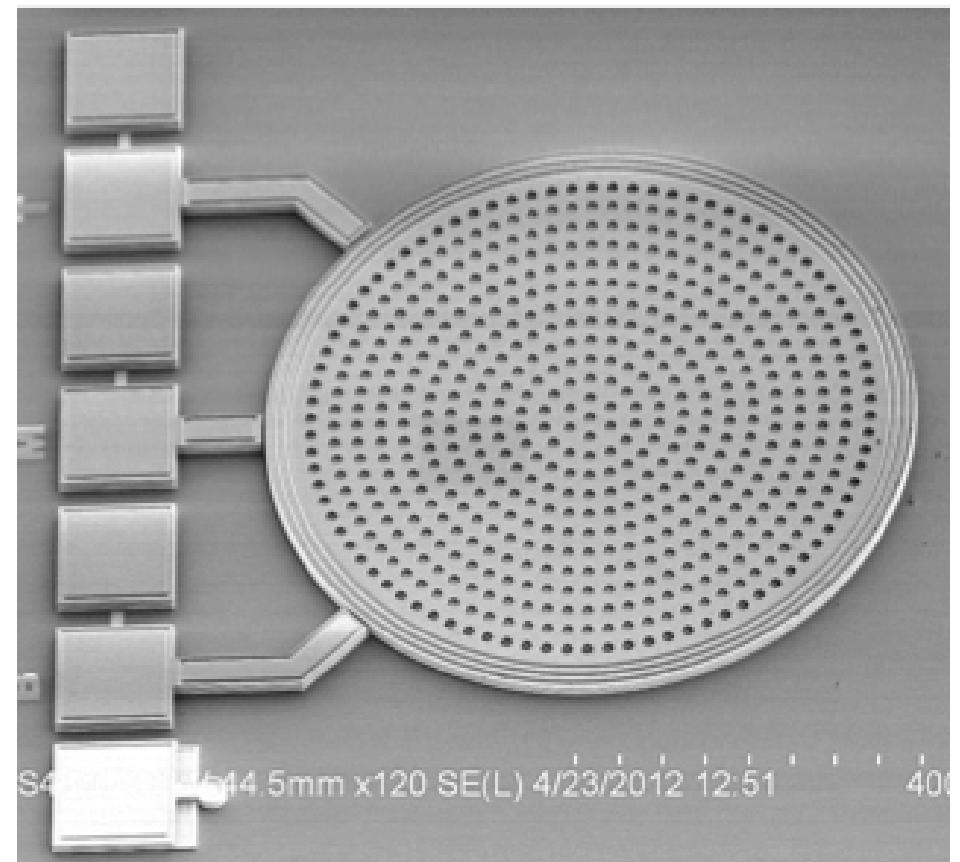
Inertial Sensors: Novel Devices

Sensing unique inertial environments



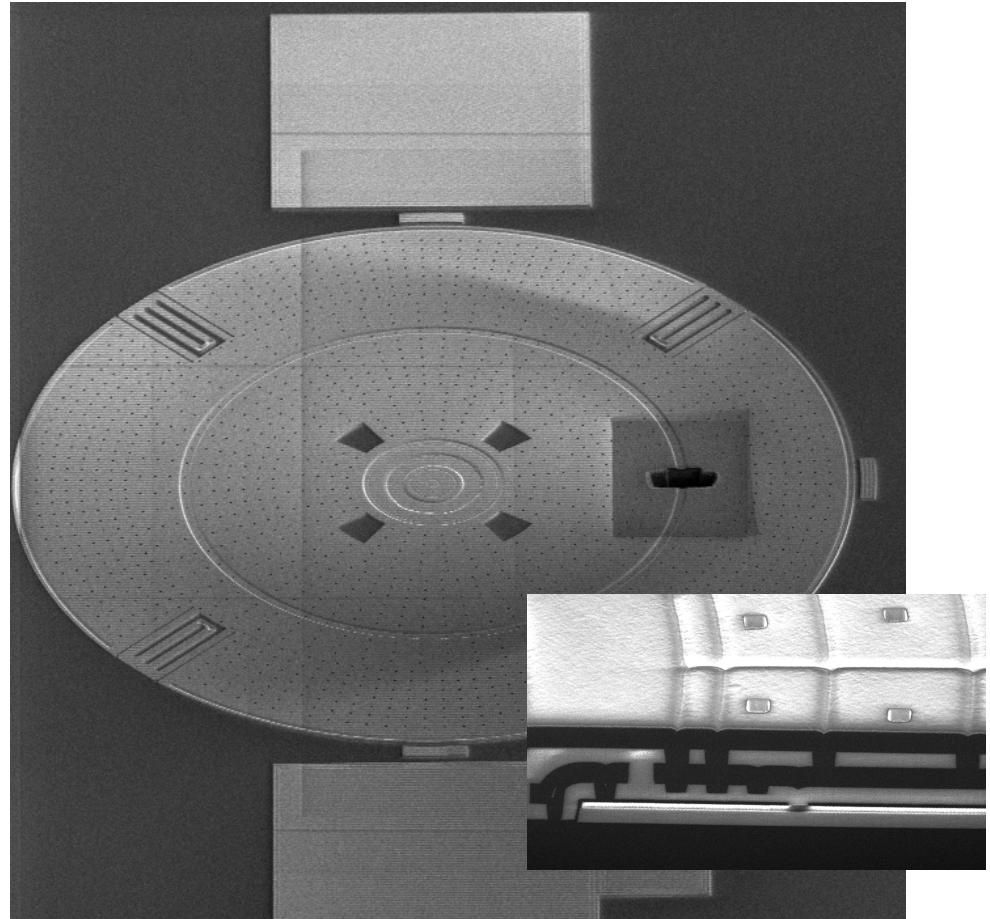
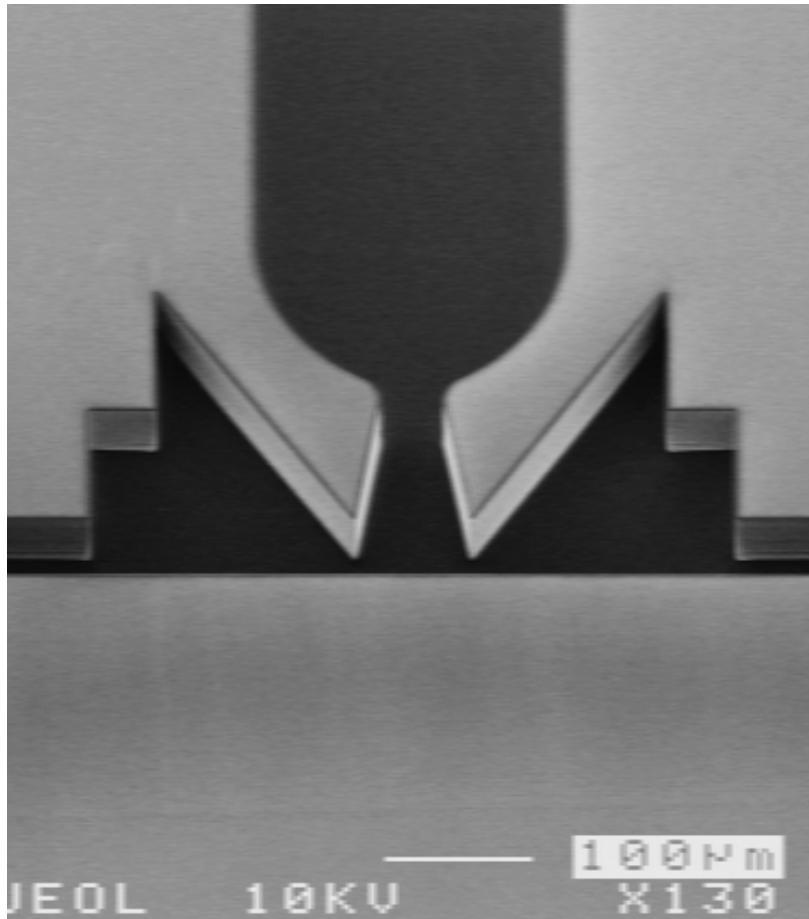
Pressure Sensors

And other moving membrane sensors, e.g., microphones



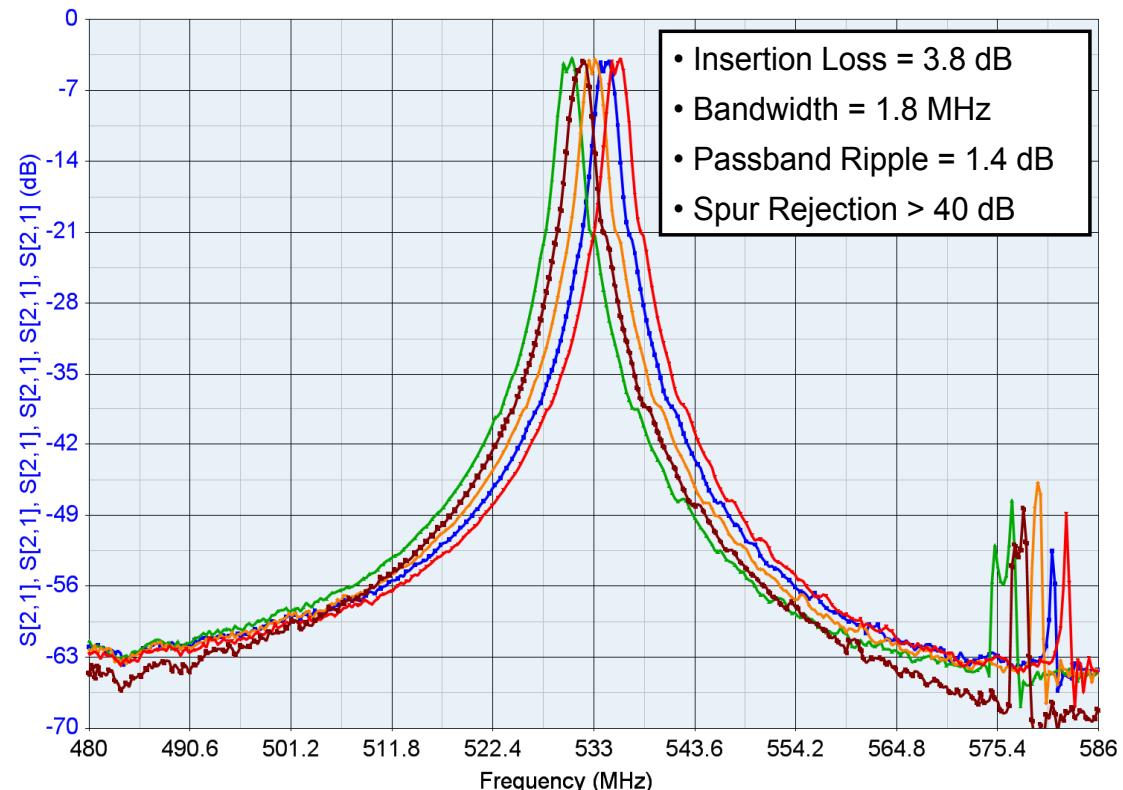
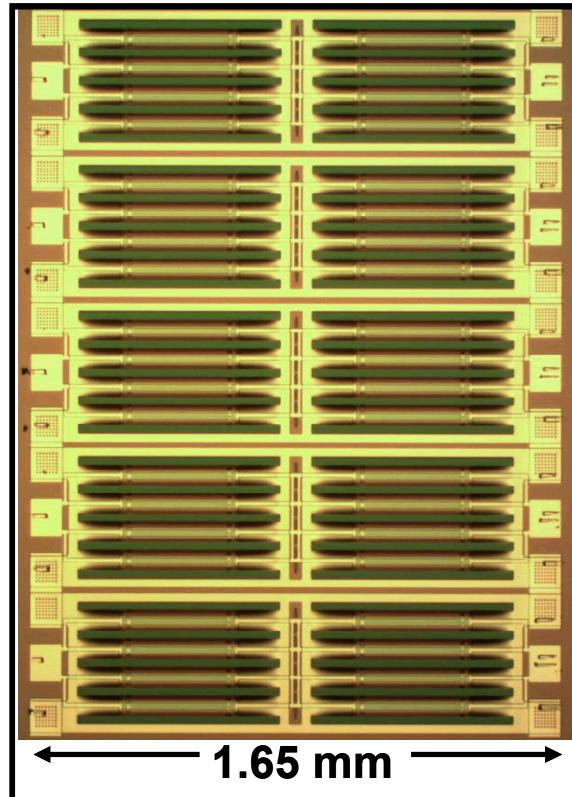
Microfluidic Actuators

Jet nozzles, active and passive valves, flow channels, and more



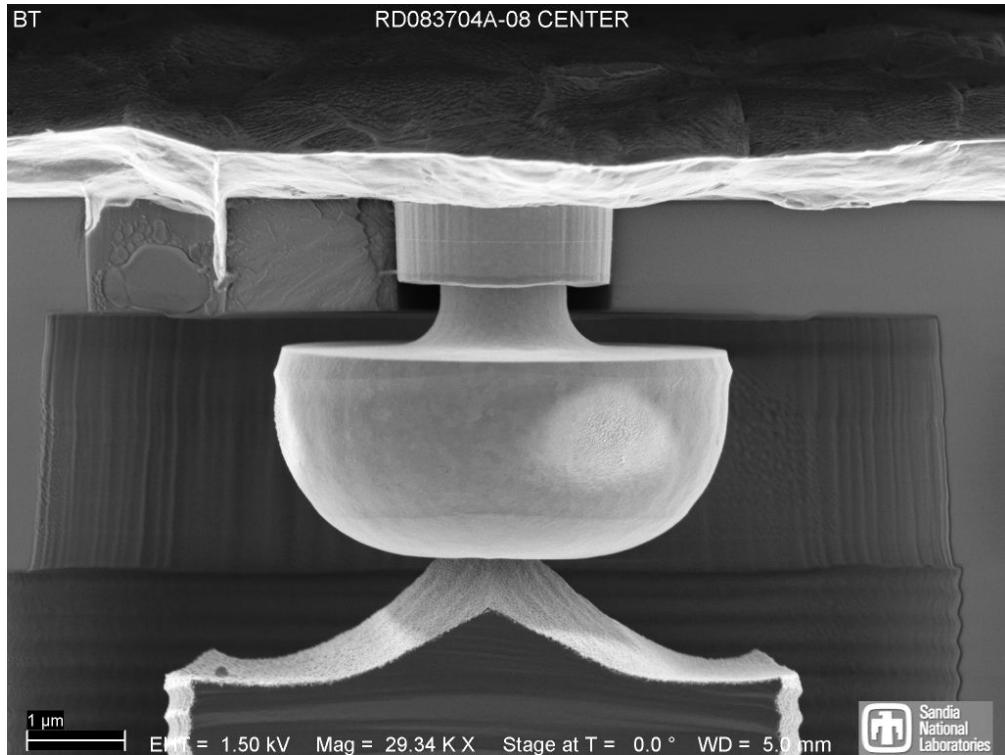
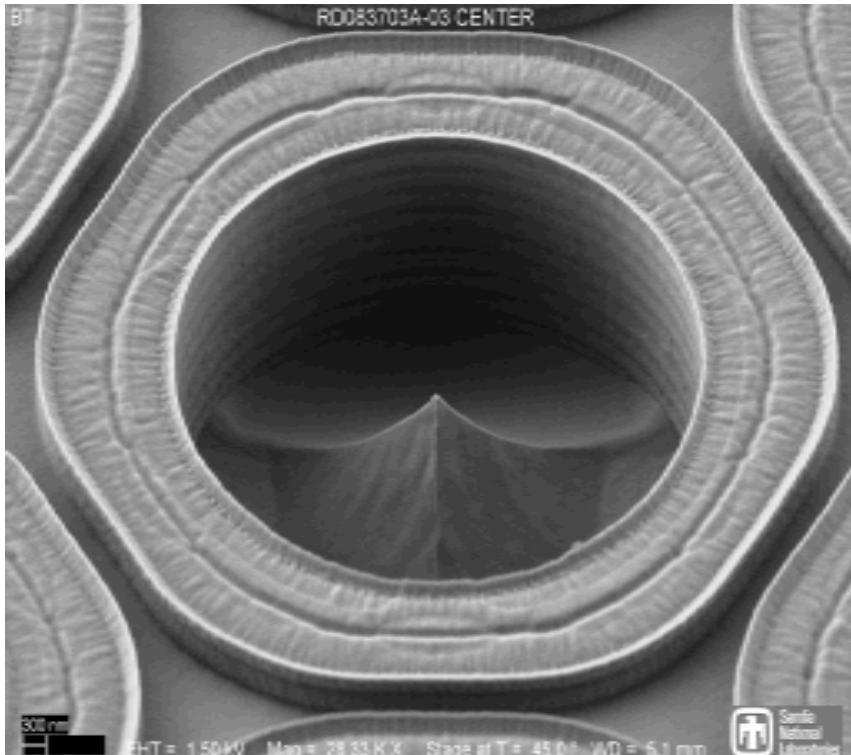
Electronics: RF Filters and Oscillators

Filter frequency defined by lithography; multiple filters on a chip



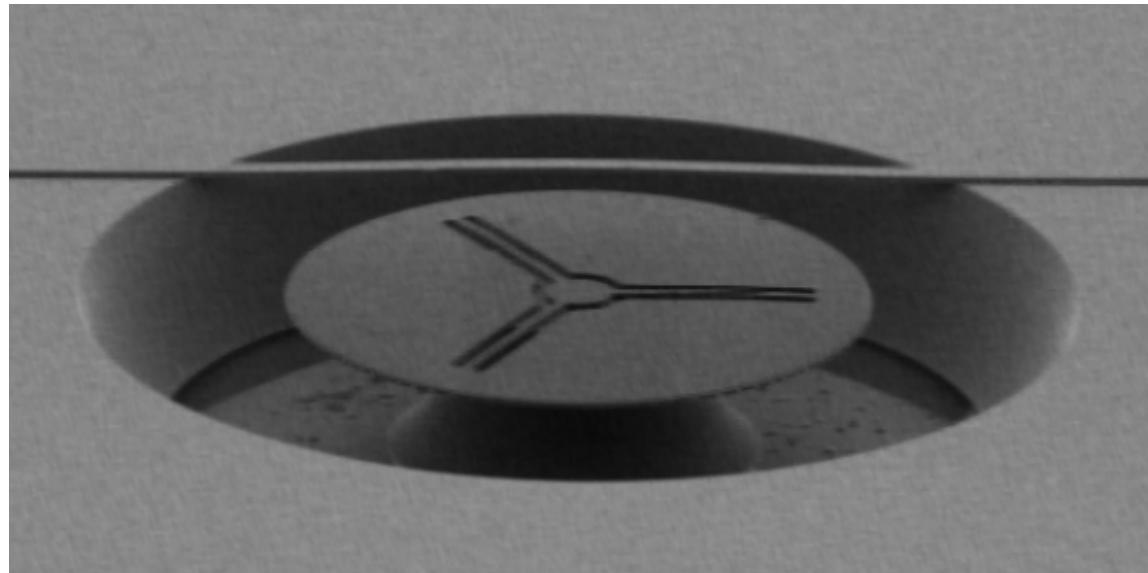
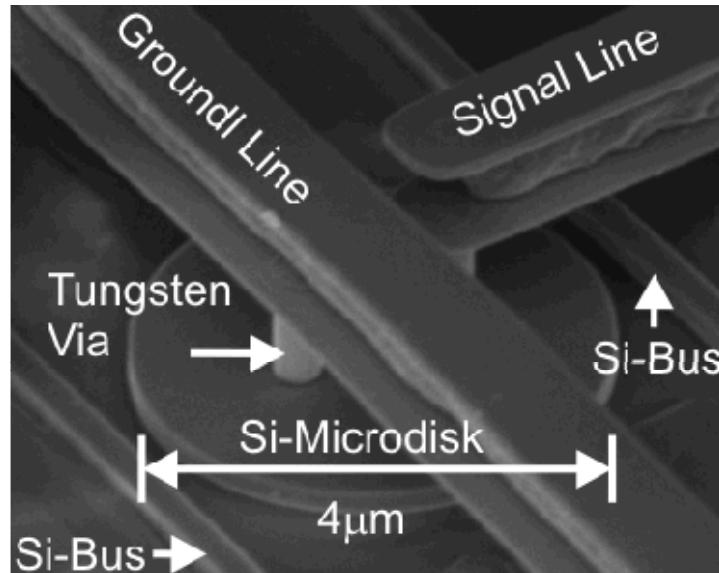
Vacuum Electronics

Monolithically fabricated vacuum devices, e.g., diode



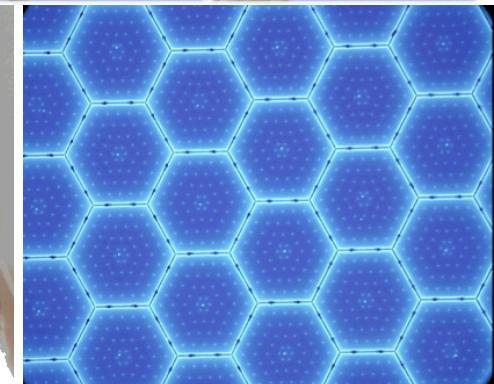
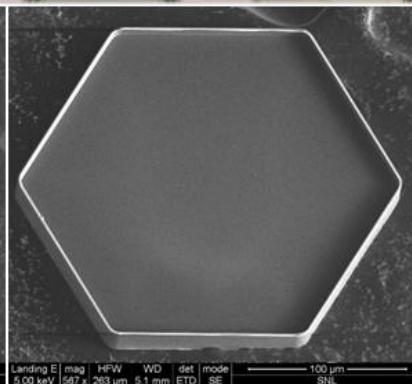
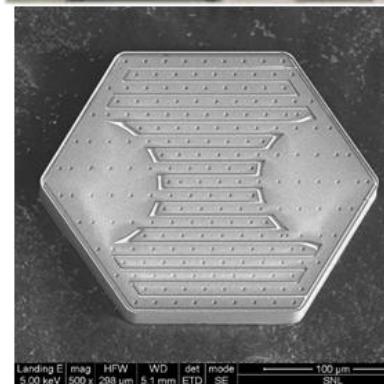
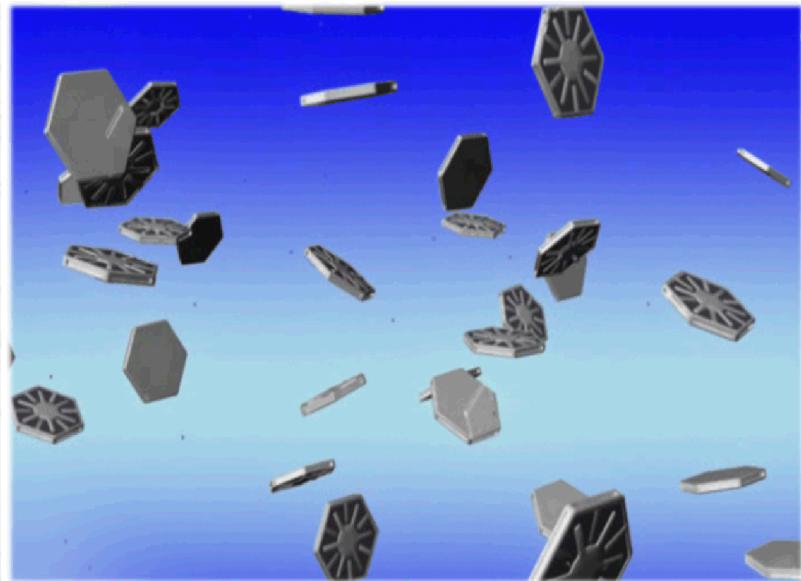
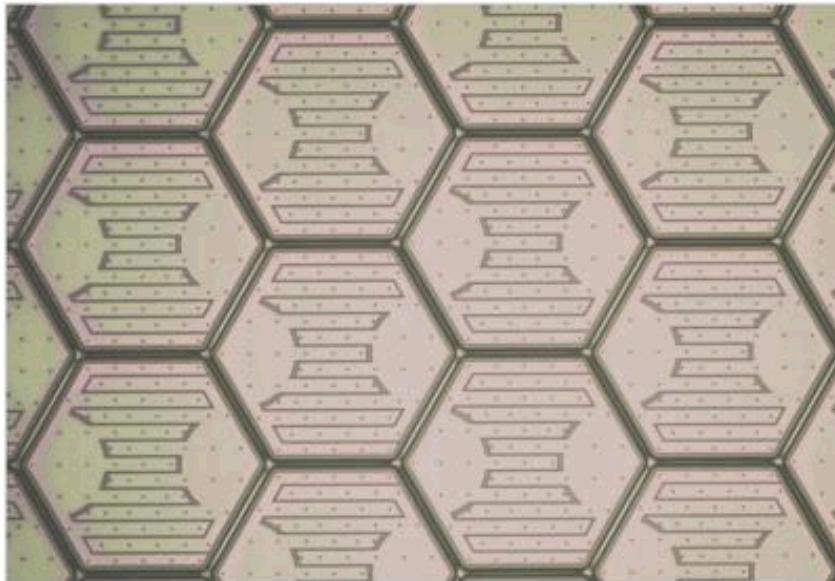
Photonics and Waveguides

Low loss waveguides and ring resonators for optical signal processing



Microsystems Enabled Photovoltaic Cells (MEPV)

Microsystems technologies are creating disruptive change in PV



Contact Information

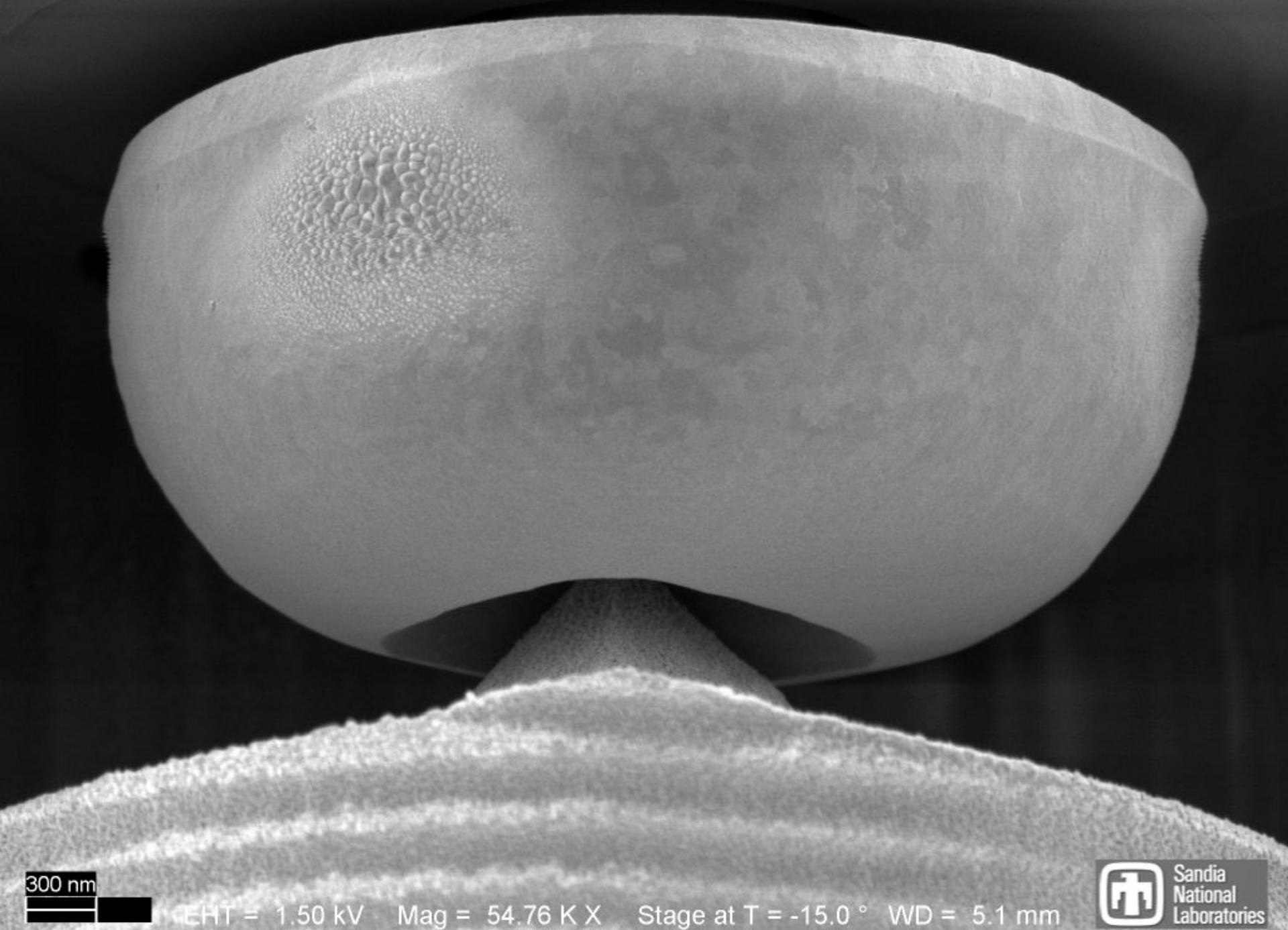
Keith Ortiz
Keith.Ortiz@sandia.gov
(505) 844-2072

www.mems.sandia.gov



BT

RD083704A-08 CENTER



300 nm

EHT = 1.50 kV Mag = 54.76 K X Stage at T = -15.0 ° WD = 5.1 mm

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